

Transparante Elektrische Circuits

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TNO | Knowledge for business

Dag van de Oppervlakte technologie 2010

Large area flexible electronics

- Lighting (OLED) and Signage (Flexible)
- Thin Film Solar cells
- Sensors in Foil

- Roll-to-Roll Production
 - Cost-effective
 - Large Area
- Plastic carriers: PET, PEN, PI
 - Dimensional stability
 - Limited Temperature stability

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Thin Film Photovoltaic's

Technology	Market Share (%)
Multicrystal	46.5%
Monocrystal	43.4%
amorphous Si	4.2%
Copper-Indium-Selenide	2.2%
Ribbon	2.6%
Cadmium-Telluride	2.7%

- Better energy output – kWh/KW
- Lower production costs
 - Less material usage (0.2 vs 10 kg / kWp)
 - Potential for lower costs throughout value chain
- Roadmap of glass-to-glass and flexible substrate
- Better aesthetics

SOURCES: Wambach et al. EU PVSEC 2007; Heise et al. EU PVSEC 2007

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Thin Film Solar Cells

- Transparent Conductive Oxides (TCOs) window layer:
 - Transparent
 - Electrical conductive

Glass / PET-foil
TCO (ZnO:Al)
a-Si:H
Back contact
(Flexible) Substrate

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Transparent Conductive Oxides

TFPV

- CuIn(Ga)Se(S)
- a-Si / mcSi
- OPV / DSC

TCO

- ZnO:Al (AZO)
- SnO₂:F (FTO) / ZnO:Al
- In₂O₃:SnO₂ (ITO)

Transparency / %

Schichtwiderstand / □ sq

Legend: ITO (red square), FTO (green square)

$$T = \left(1 + \frac{1}{2R} \sqrt{\frac{\mu_0 \sigma_{sp}}{\epsilon_0 \sigma_{dc}}} \right)^{-2} = \left(1 + \frac{188.5}{R} \frac{\sigma_{sp}}{\sigma_{dc}} \right)^{-2}$$

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Monolithic Interconnection in Thin Film PV

Glass / PET-foil
TCO
a-Si:H
Back contact
(Flexible) Substrate

ZnO:Al
Al/Ag

Maximum power densities for cells without grid

celllength (cm)

R_{Sheet} (Ω/sq)

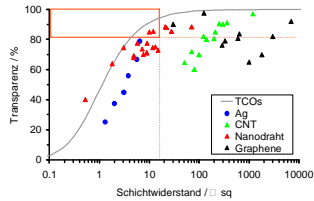
$$P_{loss} = \frac{1}{3} J_{cel}^2 \rho_{sq} W^2$$

5 – 10% resistive power losses in TCO interconnection

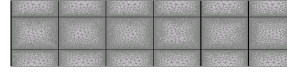
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Alternative Transparent Conductive Films

- Graphene (Nobel price 2010)
- Carbon nanotubes (CNT)
- Thin metal films (Ag, IMI)
- Metal Nano wires

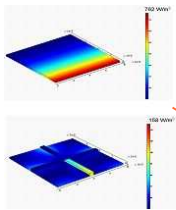


Transparent Conductive Metal Grids



- Thinner and Cheaper TCOs (Flexible foils)
- Higher Transparency of the TCO (IR-range)
- Flexibility in Cell width and Cell design
- Increased durability of TCO

Electrical modeling of TCO with grid

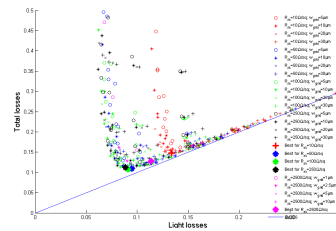


Power loss for 5 mm PV-cell

50 Ω/sq TCO
• 0.19 W m⁻¹ (~25%)

10 μm x 5 μm line grid
5% surface coverage
• 0.012 W m⁻¹ (~7%)

Modeling of the total power losses



- Simple configuration (lines, rectangular grids) are optimal
- Thin lines with low surface coverage: line widths < 50 μm
- Current concentration in grid lines: high conductivity metal

Manufacturing of Metal Grids

Requirements

- Low surface coverage
 - Minimal Shading losses
- Cost-effective
 - Metal grid deposition is an additional process
- Large area manufacturing

Manufacturing methods

- Sputtering through a Mask
- Screen printing
- Aerosol / Ink-jet printing
- **Electrodeposition**

Electrodeposition of metal grids

- High electrical conductivity
 - 1.2 - 2 times bulk Metal
 - 20-150 nΩ m

- High resolution
 - < 100 nm

- Low material losses
 - < 10% of metal
 - Additive process

- Cost-effective large area production

Electrodeposited Ag front contact for silicon solar cells:
• 0.4 % absolute efficiency gain
• 2-3 year RoI
G. Allardyce, et al, PVSEC (2007)

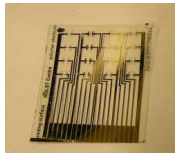
Patterned Electrodeposition @ TNO

Cost-effective electronic circuitry production



MID base for LED-Lighting

- Moulded Integrated Devices (3D-MID)
- PV front contact grids
- Flexible Electronics



Circuitry for flexible DNA sensor

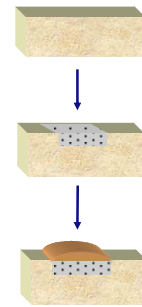
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Combining patterning and electroless deposition

Patterned (de)activation

- Injection Moulding
- Milling
- Inkjet-printing
- Micro contact printing
- Laser
- Plasma



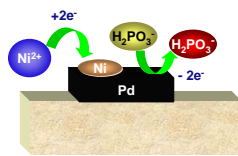
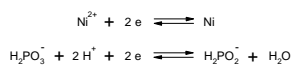
Additive metallization

- Electroless
- Electrodeposition

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Activation for electroless metal deposition



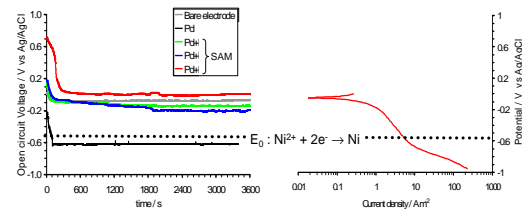
Pd catalyzed electrodeposition on non-conductive substrates

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Inhibition by Self Assembling Molecules

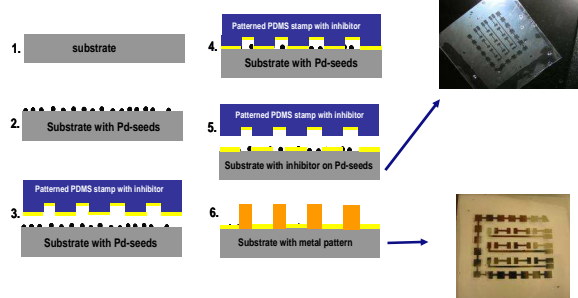
- Electroless nickel deposition is prevented by inhibition of the hypophosphite oxidation on Pd-seeds



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Micro-contact printing of inhibitors

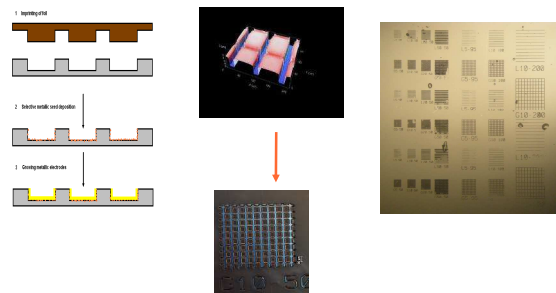


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Foil embedded grid by embossing and μCP

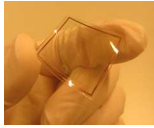
Patterned substrate



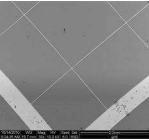
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Electrodeposited metal grids on 50 Ω/sq TCOs



PET-ITO + Cu



Glass-AZO+Ni

2% Surface coverage 20 μm wide 5 μm thick metal grids

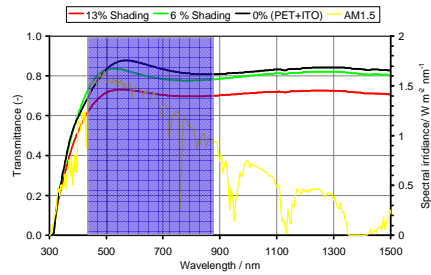
Line width	Aspekt-ratio	Surface coverage	Sheet resistance
20 μm	0.40	20%	0.05 ± 0.02 Ω/sq
60 μm	0.45	6%	0.09 ± 0.08 Ω/sq
30 μm	0.40	6%	0.12 ± 0.02 Ω/sq
30 μm	0.30	3%	0.6 ± 0.7 Ω/sq
110 μm	0.01	17%	0.6 ± 0.1 Ω/sq
160 μm	0.01	6%	1 Ω/sq

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Transmittance of TCO with grid



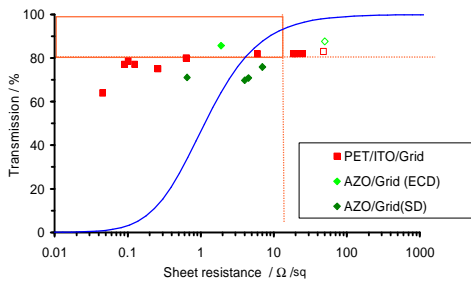
Grid surface coverage	0%	6%	13%
T _{400-800 nm} / %	83	79	70

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Transparent Conductive Metal grids



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Outlook

- TNO R2R Pilot line
 - 26 cm wide foil ; 1 m/min.
 - Patterning by micro contact printing
 - Electrochemil baths
- Cost-of-Ownership estimate
 - Costs additional Process
 - 3 – 5 € / m²
- Benefit through higher power output ?
 - Solar cells with metal grids



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Summary

- Metal grids have the potential to reduce the power losses in TCO window layers used in thin film photovoltaic cells
- Interconnection circuitry on plastic and TCOs can be achieved by
 - Patterned inhibition by SAMs
 - Selective electro(less) metal deposition
- Patterned electrodeposition is promising method to make transparent conductive layers:
 - 1 – 50 μm line width grids reduce TCOs resistance
 - 0.1 – 5 Ω sq on 50 Ω sq ITO
 - Transmittance loss of less than 10%

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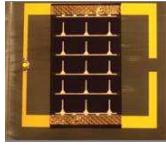
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Thank you for your attention



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